

What is claimed is:

1. A PDP firing furnace for firing a substrate of plasma display panel, comprising:

gas distribution piping laid in one direction within
5 said firing furnace and having a plurality of openings
arranged along said one direction, said gas distribution
piping being further constructed such that gas containing
oxygen is supplied via both end portions of said gas
distribution piping and said gas is supplied to an inside of
10 said firing furnace through said openings; and

gas exhaust piping for exhausting gas from within
said firing furnace,

said firing furnace being further constructed such
that said openings become larger in directions from both end
15 portions to a central portion of said gas distribution
piping, or said gas distribution piping becomes finer in
directions from said both end portions to said central
portion of said gas distribution piping.

2. The PDP firing furnace according to claim 1,
20 wherein said gas distribution piping has a separator plate
in said central portion of said gas distribution piping.

3. A PDP firing furnace for firing a substrate of plasma display panel, comprising:

gas distribution piping laid in one direction within
25 said firing furnace and having a plurality of openings
arranged along said one direction, said gas distribution
piping being further constructed such that gas containing
oxygen is supplied via both end portions of said gas

distribution piping and said gas is supplied to an inside of said firing furnace through said openings; and

gas exhaust piping for exhausting gas from within said firing furnace,

5 said firing furnace being further constructed such that said openings formed between both end portions and a central portion of said gas distribution piping are larger than said openings formed in said both end portions and central portion, or portions of said gas distribution piping
10 between said both end portions and central portion become finer than said both end portions and central portion of said gas distribution piping.

4. The PDP firing furnace according to claim 3, wherein said gas distribution piping has a separator plate
15 in said central portion of said gas distribution piping.

5. A PDP firing furnace for firing a substrate of plasma display panel, comprising:

gas distribution piping laid in one direction within said firing furnace and having a plurality of openings
20 arranged along said one direction, said gas distribution piping being further constructed such that gas containing oxygen is supplied via one end portion of said gas distribution piping and said gas is supplied to an inside of said firing furnace through said openings; and

25 gas exhaust piping for exhausting gas from within said firing furnace,

 said firing furnace being further constructed such that said openings become larger in directions from both end

portions of said gas distribution piping to a portion between said both end portions, or said gas distribution piping becomes finer in directions from said both end portions of said gas distribution piping to said portion
5 between said both end portions.

6. The PDP firing furnace according to claim 5, wherein said gas distribution piping has a separator plate in said central portion of said gas distribution piping.

7. A PDP firing furnace for firing a substrate of
10 plasma display panel, comprising:

gas distribution piping for supplying gas containing oxygen to an inside of said firing furnace; and

gas exhaust piping laid in one direction within said firing furnace and having a plurality of openings arranged
15 along said one direction, said gas exhaust piping being further constructed such that gas is exhausted via both end portions of said gas exhaust piping to exhaust gas from within said firing furnace through said openings,

said firing furnace being further constructed such
20 that said openings become larger in directions from both end portions to a central portion of said gas exhaust piping, or said gas exhaust piping becomes finer in directions from said both end portions to central portion of said gas exhaust piping.

25 8. The PDP firing furnace according to claim 7, wherein said gas exhaust piping has a separator plate in said central portion of said gas exhaust piping.

9. A PDP firing furnace for firing a substrate of

plasma display panel, comprising:

gas distribution piping for supplying gas containing oxygen to an inside of said firing furnace; and

gas exhaust piping laid in one direction within said firing furnace and having a plurality of openings arranged along said one direction, said gas exhaust piping being further constructed such that gas is exhausted via both end portions of said gas exhaust piping to exhaust gas from within said firing furnace through said openings,

said firing furnace being further constructed such that said openings formed between both end portions and a central portion of said gas exhaust piping are larger than said openings formed in said both end portions and central portion, or portions of said gas exhaust piping between said both end portions and central portion are finer than said both end portions and central portion of said gas exhaust piping.

10. The PDP firing furnace according to claim 9, wherein said gas exhaust piping has a separator plate in said central portion of said gas exhaust piping.

11. A PDP firing furnace for firing a substrate of plasma display panel, comprising:

gas distribution piping for supplying gas containing oxygen to an inside of said firing furnace; and

gas exhaust piping laid in one direction within said firing furnace and having a plurality of openings arranged along said one direction, said gas exhaust piping being further constructed such that gas is exhausted via both end

portions of said gas exhaust piping to exhaust gas from within said firing furnace through said openings,

said firing furnace being further constructed such that said openings become larger in directions from both end portions of said gas exhaust piping to a portion between said both end portions, or said gas exhaust piping becomes finer in directions from said both end portions of said gas exhaust piping to said portion between said both end portions.

10 12. The PDP firing furnace according to claim 11, wherein said gas exhaust piping has a separator plate in said central portion of said gas exhaust piping.

13. A PDP firing furnace for firing a substrate of plasma display panel, comprising:

15 gas distribution piping laid in one direction within said firing furnace and having a plurality of openings arranged along said one direction, said gas distribution piping being further constructed such that gas containing oxygen is supplied via one end portion of said gas distribution piping and said gas is supplied to an inside of said firing furnace through said openings; and

gas exhaust piping for exhausting gas from within said firing furnace,

25 said firing furnace being further constructed such that said openings become larger in directions from both end portions of said gas distribution piping to a portion between said both end portions, or said gas distribution piping becomes finer in directions from said both end

portions of said gas distribution piping to said portion between said both end portions.

14. A PDP firing furnace for firing a substrate of plasma display panel, comprising:

5 gas distribution piping for supplying gas containing oxygen to an inside of said firing furnace; and

 gas exhaust piping laid in one direction within said firing furnace and having a plurality of openings arranged along said one direction, said gas exhaust piping being
10 further constructed such that gas is exhausted via one end portion of said gas exhaust piping to exhaust gas from within said firing furnace through said openings,

 said firing furnace being further constructed such that said openings become larger in a direction from said
15 one end portion, through which said gas is exhausted, to the other end portion of said gas exhaust piping, or said gas exhaust piping becomes finer in a direction from said one end portion, through which said gas is exhausted, to the other end portion of said gas exhaust piping.

20 15. The PDP firing furnace according to claim 1, wherein said openings have a shape of circle, ellipse or rectangle.

 16. The PDP firing furnace according to claim 1, further comprising:

25 a carrier unit for transporting said substrate;

 a plurality of furnace compartments arranged along a direction of movement of said substrate and allowing said substrate to pass sequentially through an inside of said

furnace compartments; and

a heating unit for heating said substrate,

wherein said gas distribution piping and gas exhaust
piping are laid in a direction orthogonal to said direction
5 of movement of said substrate or in the same direction as
said direction of movement of said substrate within said
firing furnace.

17. A method of manufacturing a plasma display panel,
comprising the steps of:

10 forming a paste layer made of a transparent
conductive material on a first substrate and firing said
paste layer to form a transparent electrode;

forming a paste layer made of a transparent
dielectric material over said transparent electrode and
15 firing said paste layer to form a transparent dielectric
layer;

forming electrodes on a second substrate;

forming a paste layer made of a dielectric material
over said electrodes and firing said paste layer to form a
20 dielectric layer;

forming a paste layer made of a barrier rib material
on said dielectric layer and firing said paste layer to form
barrier ribs; and

forming a paste layer made of a phosphor material on
25 at least one of said dielectric layer and side faces of said
barrier ribs and firing said paste layer to form phosphor
layers,

said method being further constructed such that in at

least one of the step of forming said transparent electrode,
the step of forming said transparent dielectric layer, the
step of forming said dielectric layer, the step of forming
said barrier ribs, and the step of forming said phosphor
5 layers, said firing of said paste layer is carried out
within the firing furnace described in claim 1.

18. A method of manufacturing a plasma display panel,
comprising the steps of:

forming a paste layer made of a transparent
10 conductive material on a first substrate and firing said
paste layer to form a transparent electrode;

forming a paste layer made of a transparent
dielectric material over said transparent electrode and
firing said paste layer to form a transparent dielectric
15 layer;

forming electrodes on a second substrate;

forming a paste layer made of a dielectric material
over said electrodes and firing said paste layer to form a
dielectric layer;

20 forming a paste layer made of a barrier rib material
on said dielectric layer and firing said paste layer to form
barrier ribs; and

forming a paste layer made of a phosphor material on
at least one of said dielectric layer and side faces of said
25 barrier ribs and firing said paste layer to form phosphor
layers,

said method being further constructed such that in at
least one of the step of forming said transparent electrode,

the step of forming said transparent dielectric layer, the step of forming said dielectric layer, the step of forming said barrier ribs, and the step of forming said phosphor layers, said firing of said paste layer is carried out
5 within the firing furnace described in claim 3.

19. A method of manufacturing a plasma display panel, comprising the steps of:

forming a paste layer made of a transparent conductive material on a first substrate and firing said
10 paste layer to form a transparent electrode;

forming a paste layer made of a transparent dielectric material over said transparent electrode and firing said paste layer to form a transparent dielectric layer;

15 forming electrodes on a second substrate;

forming a paste layer made of a dielectric material over said electrodes and firing said paste layer to form a dielectric layer;

forming a paste layer made of a barrier rib material
20 on said dielectric layer and firing said paste layer to form barrier ribs; and

forming a paste layer made of a phosphor material on at least one of said dielectric layer and side faces of said barrier ribs and firing said paste layer to form phosphor
25 layers,

said method being further constructed such that in at least one of the step of forming said transparent electrode, the step of forming said transparent dielectric layer, the

step of forming said dielectric layer, the step of forming said barrier ribs, and the step of forming said phosphor layers, said firing of said paste layer is carried out within the firing furnace described in claim 5.

5 20. A method of manufacturing a plasma display panel, comprising the steps of:

 forming a paste layer made of a transparent conductive material on a first substrate and firing said paste layer to form a transparent electrode;

10 forming a paste layer made of a transparent dielectric material over said transparent electrode and firing said paste layer to form a transparent dielectric layer;

 forming electrodes on a second substrate;

15 forming a paste layer made of a dielectric material over said electrodes and firing said paste layer to form a dielectric layer;

 forming a paste layer made of a barrier rib material on said dielectric layer and firing said paste layer to form
20 barrier ribs; and

 forming a paste layer made of a phosphor material on at least one of said dielectric layer and side faces of said barrier ribs and firing said paste layer to form phosphor layers,

25 said method being further constructed such that in at least one of the step of forming said transparent electrode, the step of forming said transparent dielectric layer, the step of forming said dielectric layer, the step of forming

said barrier ribs, and the step of forming said phosphor layers, said firing of said paste layer is carried out within the firing furnace described in claim 7.

21. A method of manufacturing a plasma display panel,
5 comprising the steps of:

forming a paste layer made of a transparent conductive material on a first substrate and firing said paste layer to form a transparent electrode;

forming a paste layer made of a transparent
10 dielectric material over said transparent electrode and firing said paste layer to form a transparent dielectric layer;

forming electrodes on a second substrate;

forming a paste layer made of a dielectric material
15 over said electrodes and firing said paste layer to form a dielectric layer;

forming a paste layer made of a barrier rib material on said dielectric layer and firing said paste layer to form barrier ribs; and

20 forming a paste layer made of a phosphor material on at least one of said dielectric layer and side faces of said barrier ribs and firing said paste layer to form phosphor layers,

said method being further constructed such that in at
25 least one of the step of forming said transparent electrode, the step of forming said transparent dielectric layer, the step of forming said dielectric layer, the step of forming said barrier ribs, and the step of forming said phosphor

layers, said firing of said paste layer is carried out within the firing furnace described in claim 9.

22. A method of manufacturing a plasma display panel, comprising the steps of:

5 forming a paste layer made of a transparent conductive material on a first substrate and firing said paste layer to form a transparent electrode;

 forming a paste layer made of a transparent dielectric material over said transparent electrode and
10 firing said paste layer to form a transparent dielectric layer;

 forming electrodes on a second substrate;

 forming a paste layer made of a dielectric material over said electrodes and firing said paste layer to form a
15 dielectric layer;

 forming a paste layer made of a barrier rib material on said dielectric layer and firing said paste layer to form barrier ribs; and

 forming a paste layer made of a phosphor material on
20 at least one of said dielectric layer and side faces of said barrier ribs and firing said paste layer to form phosphor layers,

 said method being further constructed such that in at least one of the step of forming said transparent electrode,
25 the step of forming said transparent dielectric layer, the step of forming said dielectric layer, the step of forming said barrier ribs, and the step of forming said phosphor layers, said firing of said paste layer is carried out

within the firing furnace described in claim 11.

23. A method of manufacturing a plasma display panel, comprising the steps of:

forming a paste layer made of a transparent
5 conductive material on a first substrate and firing said
paste layer to form a transparent electrode;

forming a paste layer made of a transparent
dielectric material over said transparent electrode and
firing said paste layer to form a transparent dielectric
10 layer;

forming electrodes on a second substrate;

forming a paste layer made of a dielectric material
over said electrodes and firing said paste layer to form a
dielectric layer;

15 forming a paste layer made of a barrier rib material
on said dielectric layer and firing said paste layer to form
barrier ribs; and

forming a paste layer made of a phosphor material on
at least one of said dielectric layer and side faces of said
20 barrier ribs and firing said paste layer to form phosphor
layers,

said method being further constructed such that in at
least one of the step of forming said transparent electrode,
the step of forming said transparent dielectric layer, the
25 step of forming said dielectric layer, the step of forming
said barrier ribs, and the step of forming said phosphor
layers, said firing of said paste layer is carried out
within the firing furnace described in claim 13.

24. A method of manufacturing a plasma display panel, comprising the steps of:

forming a paste layer made of a transparent
conductive material on a first substrate and firing said
5 paste layer to form a transparent electrode;

forming a paste layer made of a transparent
dielectric material over said transparent electrode and
firing said paste layer to form a transparent dielectric
layer;

10 forming electrodes on a second substrate;

forming a paste layer made of a dielectric material
over said electrodes and firing said paste layer to form a
dielectric layer;

forming a paste layer made of a barrier rib material
15 on said dielectric layer and firing said paste layer to form
barrier ribs; and

forming a paste layer made of a phosphor material on
at least one of said dielectric layer and side faces of said
barrier ribs and firing said paste layer to form phosphor
20 layers,

said method being further constructed such that in at
least one of the step of forming said transparent electrode,
the step of forming said transparent dielectric layer, the
step of forming said dielectric layer, the step of forming
25 said barrier ribs, and the step of forming said phosphor
layers, said firing of said paste layer is carried out
within the firing furnace described in claim 14.